



**Anton Paar**



# ZETA POTENTIAL AS AN INDICATOR OF SOLID SURFACE CHEMICAL PROPERTIES

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# Anton Paar GmbH



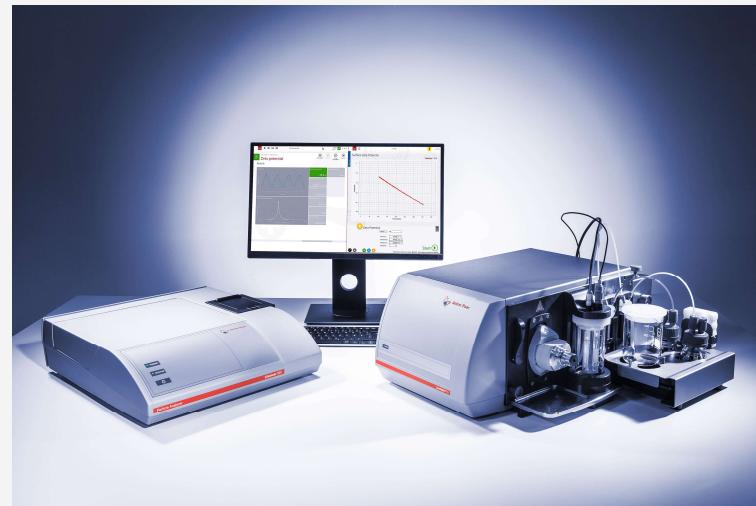
**Anton Paar develops, produces, and distributes analytical instruments for laboratories as well as process measuring systems, and provides custom-tailored automation and robotic solutions.**

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## Zeta potential analysis

### Instrumentation



3.8 nm

**Litesizer 500**

Electrophoretic Light Scattering

100 µm

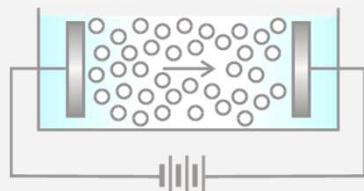
25 µm

unlimited

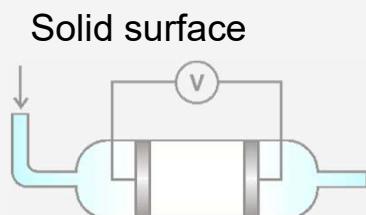
**SurPASS 3**  
Streaming Potential

D851A004EN-D

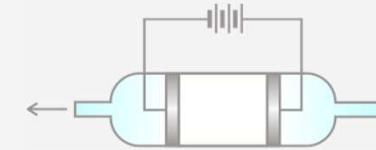
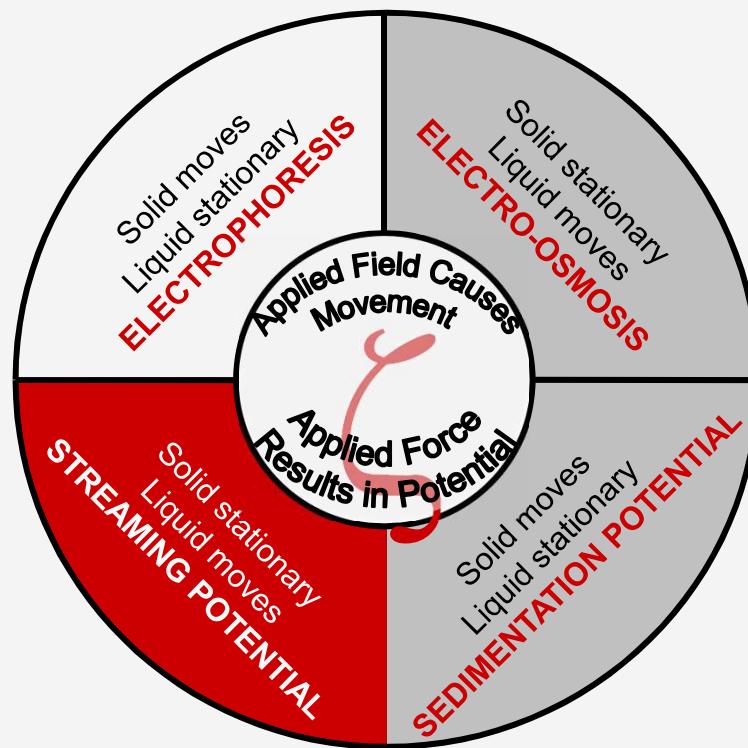
## Electrokinetic effects



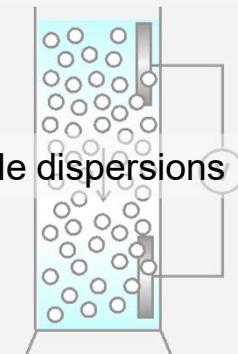
Particle dispersions  
Emulsions



Solid surface



Porous plugs



Particle dispersions



## SurPASS™ 3

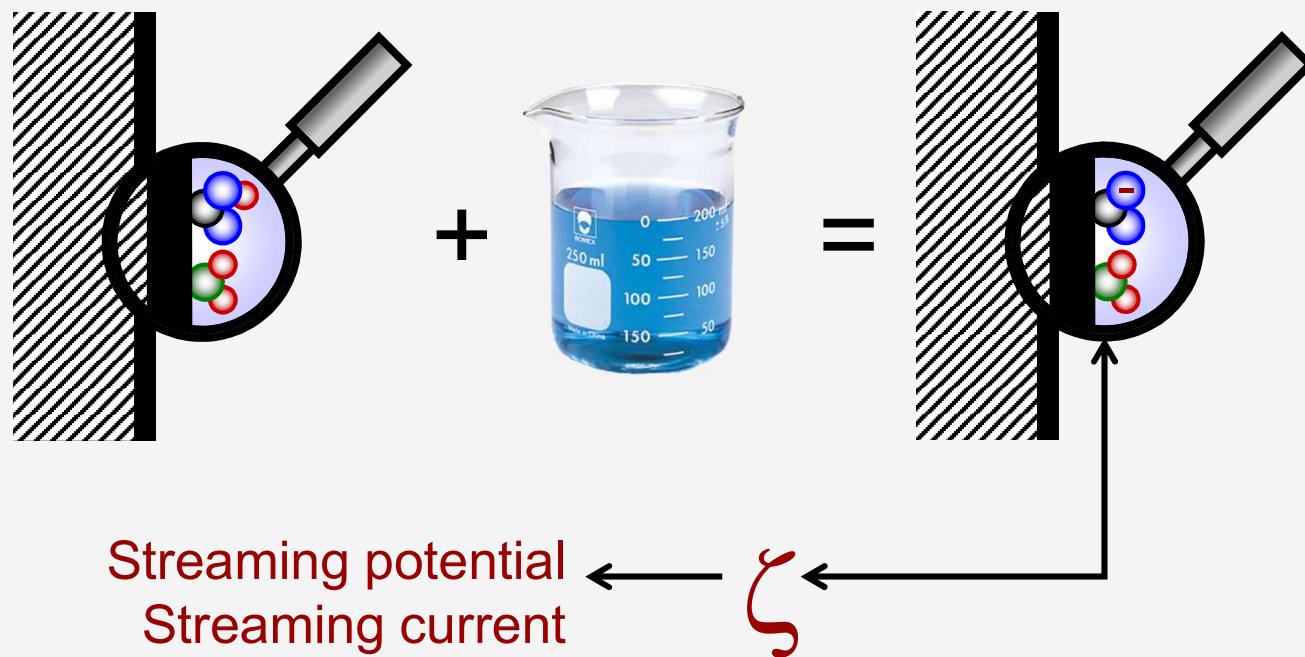
### SurPASS™ 3 Electrokinetic Analyzer for Solid Surface Analysis

determines the zeta potential on  
macroscopic solid surfaces

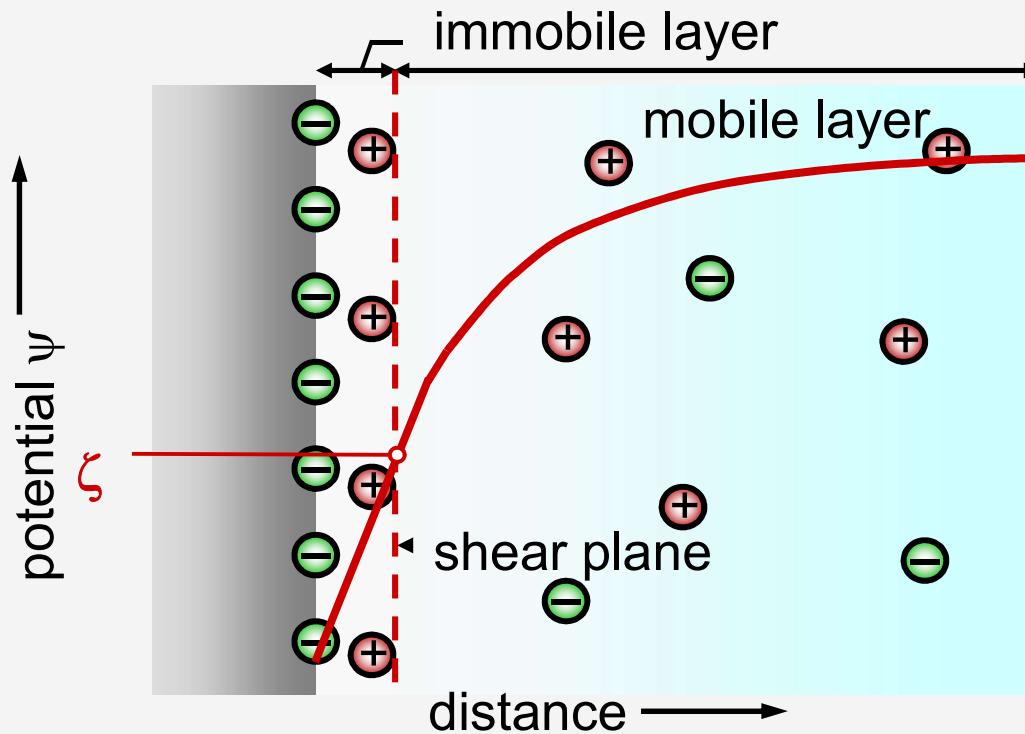


D85IA004EN-C Nr. | 6

## Concept of surface zeta potential



## Electric double layer



## Solid surface zeta potential

### Surface characterization

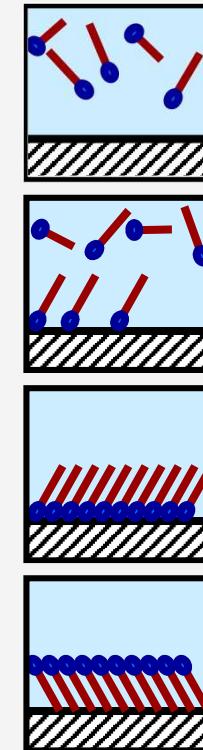
- Surface chemistry: acidic and basic functional groups
- Wettability: Hydrophilic / hydrophobic properties

### Surface modification

- Chemical and physical surface treatment

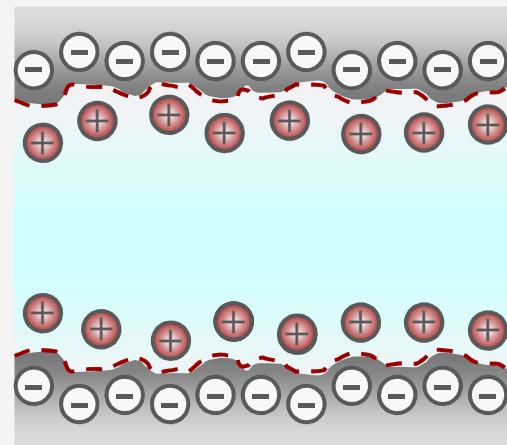
### Adsorption studies

- Adsorption from the liquid phase on the solid surface

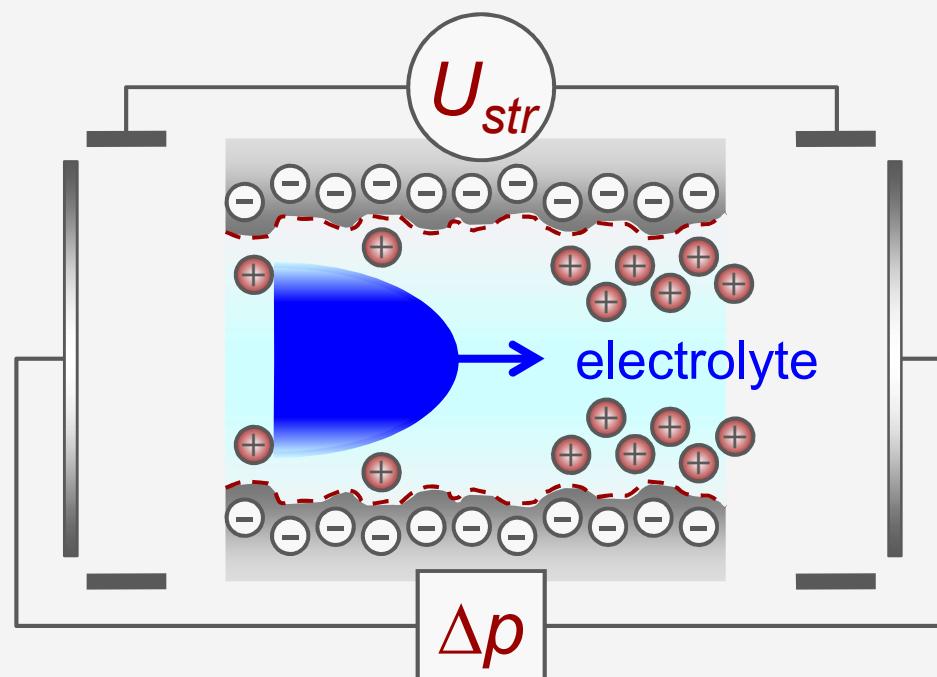


## Streaming potential

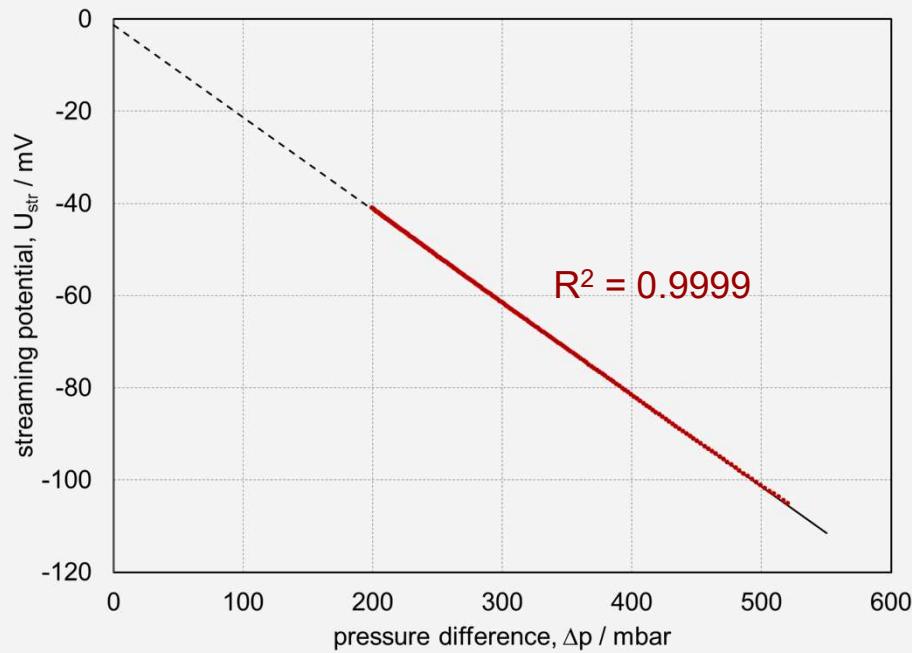
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## Streaming potential



## Measuring principle

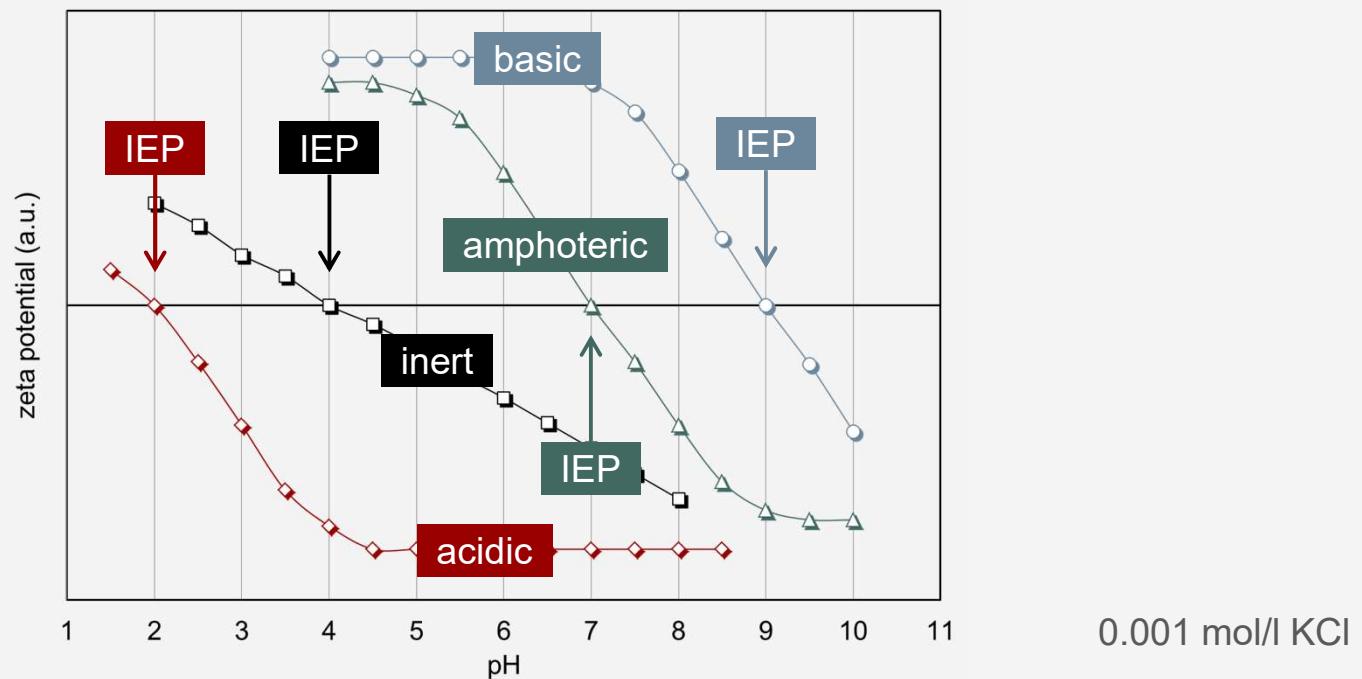


$$\zeta = \frac{dU_{str}}{d\Delta p} \times \frac{\eta}{\epsilon_r \times \epsilon_0} \times \kappa_B$$

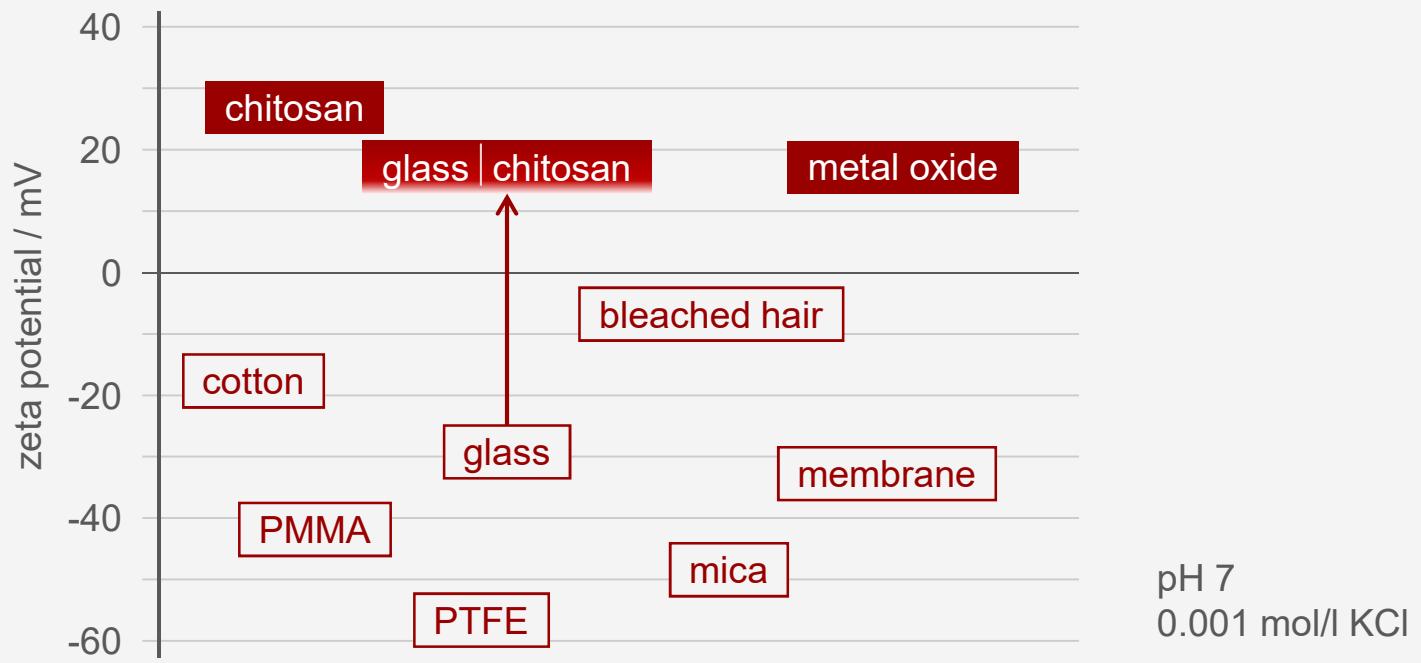
$$\zeta = \frac{dI_{str}}{d\Delta p} \times \frac{\eta}{\epsilon_r \times \epsilon_0} \times \frac{L}{A}$$

- $U_{str}$  ..... streaming potential
- $I_{str}$  ..... streaming current
- $\Delta p$  ..... pressure difference
- $\eta$  ..... viscosity
- $\epsilon_r \times \epsilon_0$  ..... dielectric permittivity
- $\kappa_B$  ..... electrolyte conductivity
- $L/A$  ..... cell constant

## pH dependence

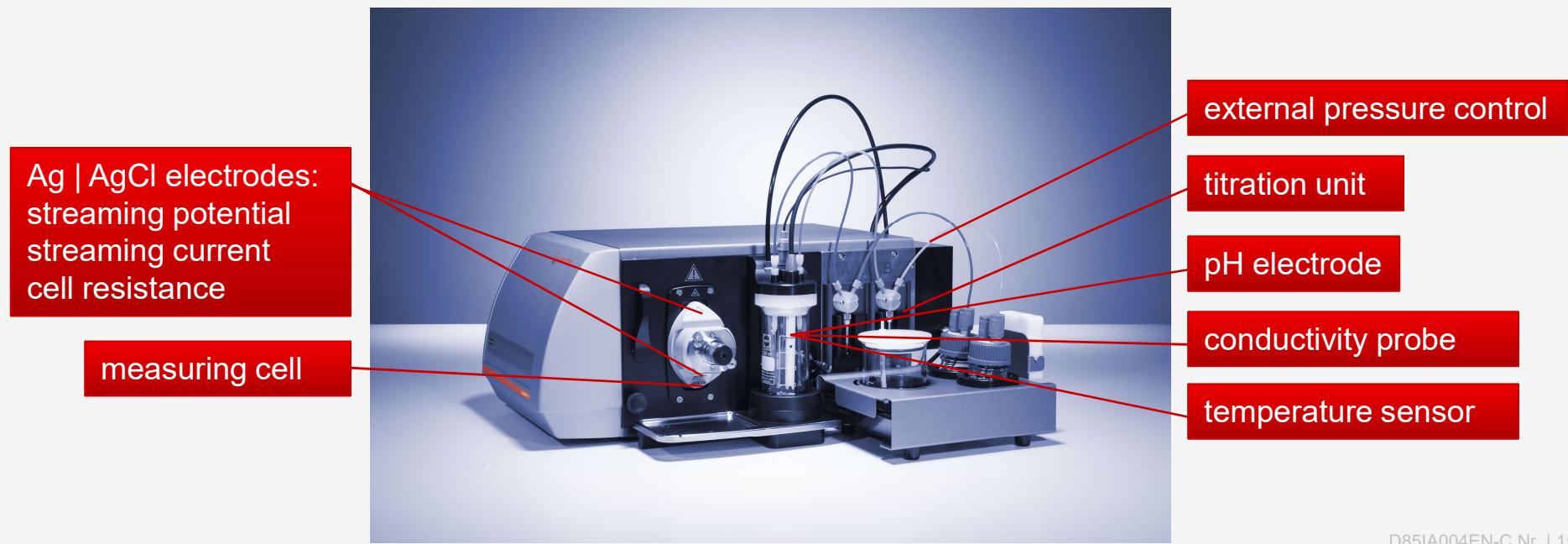


## Single zeta potential



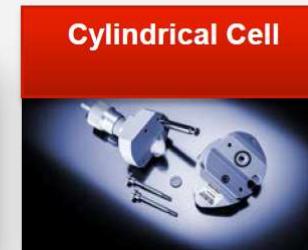
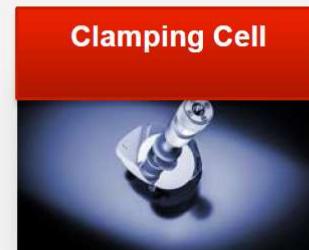
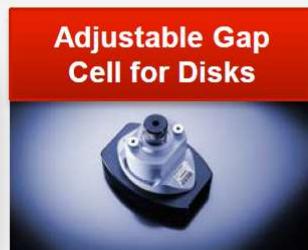
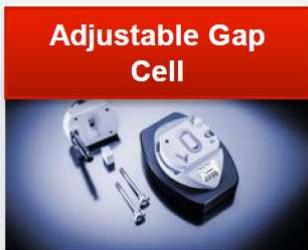
## SurPASS™ 3

The high-end electrokinetic analyzer for fully automated analysis



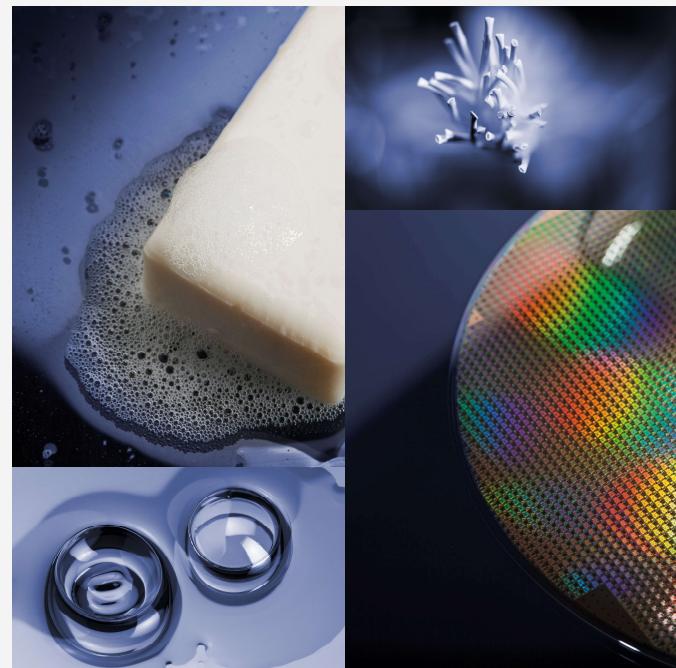


## SurPASS 3 measuring cells

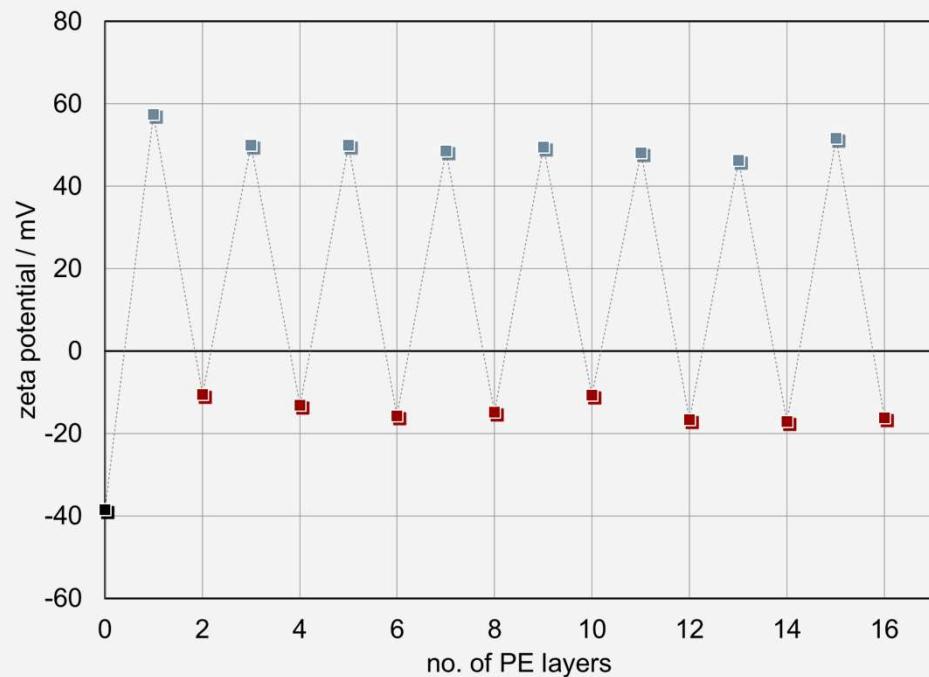


## SurPASS™ 3 applications

- Membranes and filters
- Biomaterials
- Semiconductors
- Fibers and fabrics
- Cosmetics and detergents
- Minerals
- Polymers
  
- and many more



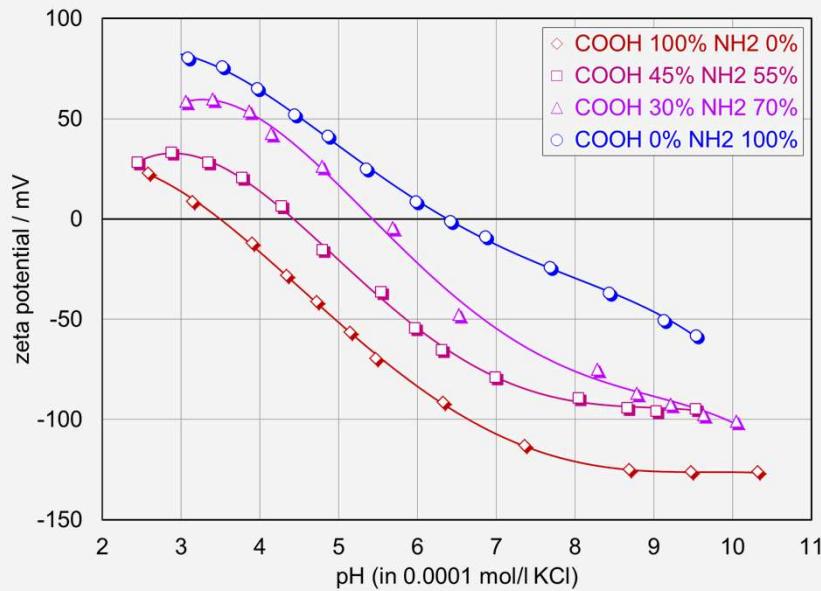
## Polyelectrolyte multilayer



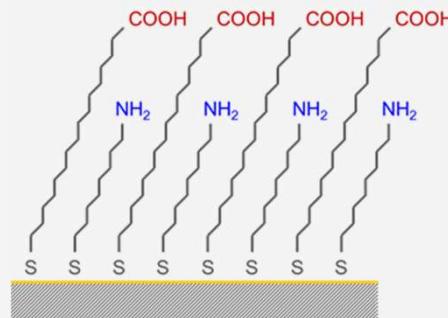
- PLL | CS multilayer on glass  
PLL ..... poly(L-lysine)  
CS ..... chondroitin sulfate
- Polyelectrolyte deposition in 0.025 M HEPES, 0.137 M NaCl, pH 7.4
- $\zeta$ -analysis in 0.001 mol/l NaCl, pH 5.5

## SurPASS 3 for semiconductor applications

Self-assembled monolayers: Sensitivity of zeta potential

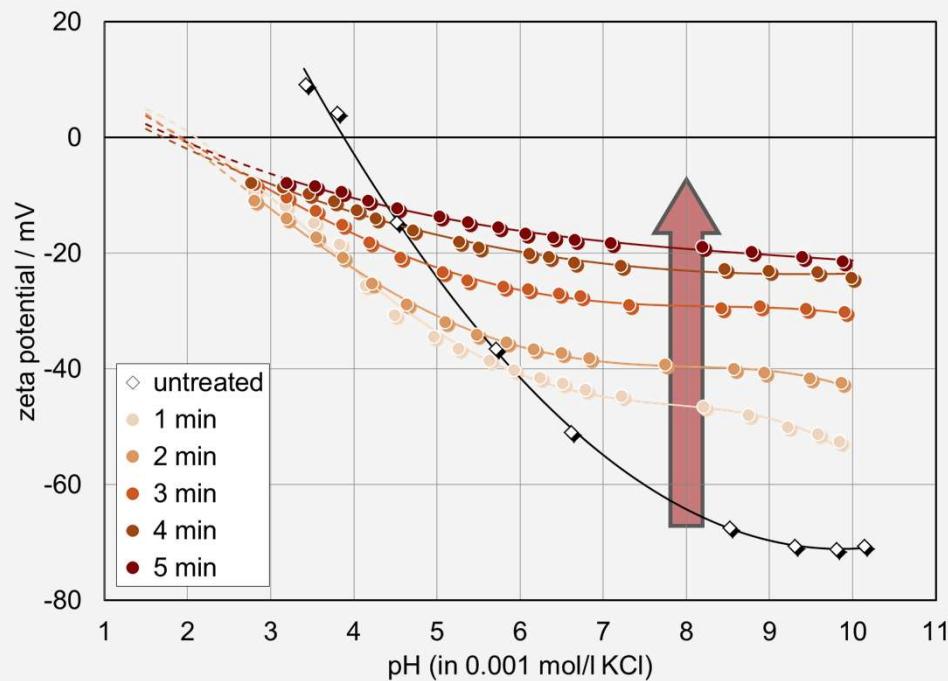


- SAM of thiols with carboxylic acid and amine terminal groups on gold surface
- $\text{HS} - (\text{CH}_2)_{15} - \text{COOH}$
- $\text{HS} - (\text{CH}_2)_8 - \text{NH}_2$

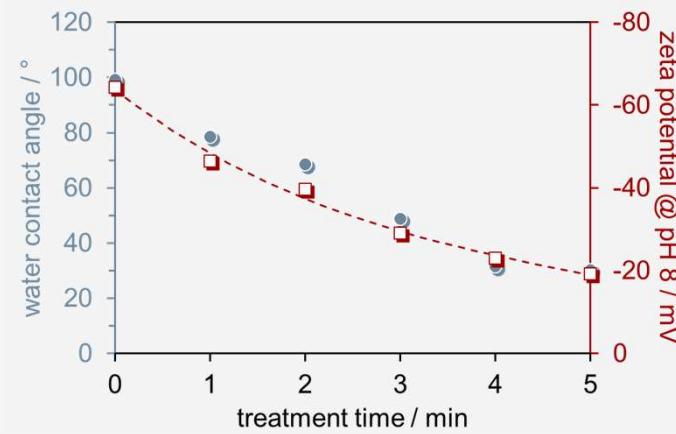


Lin et al., Phys. Chem. Chem. Phys. 11 (2009) 6199

## Polymer surface activation

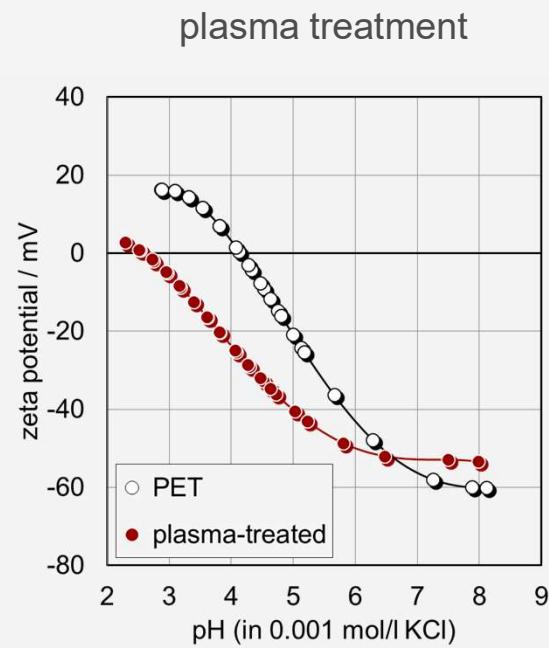
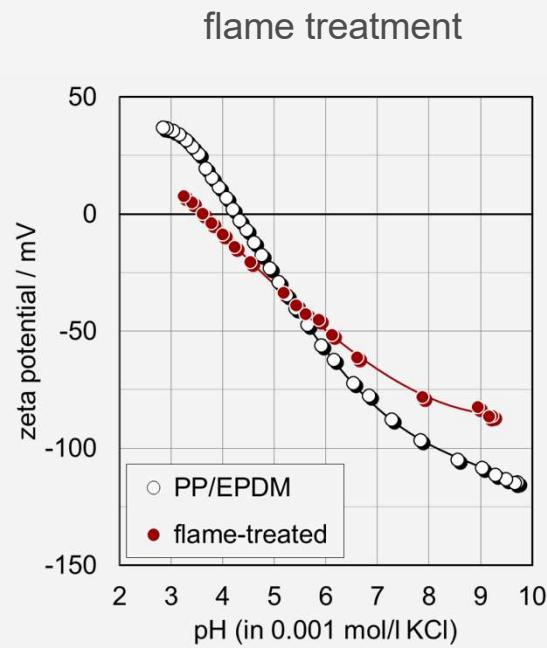
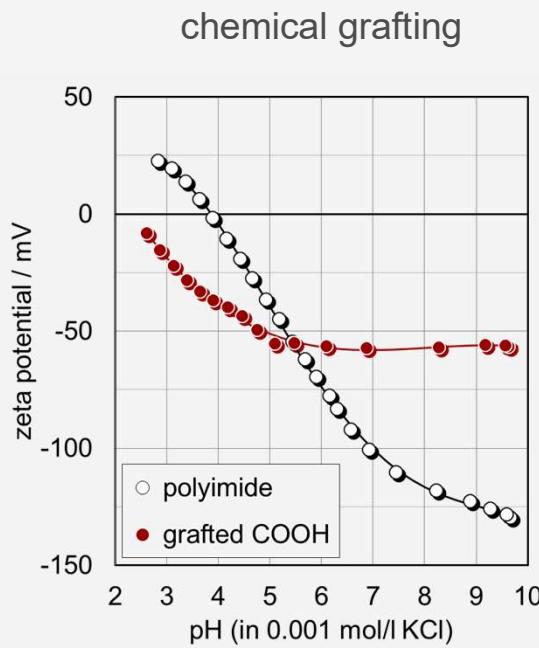


- Modification of polyethylene foil thereby retaining bulk properties
- Introducing acidic groups by photochemical process

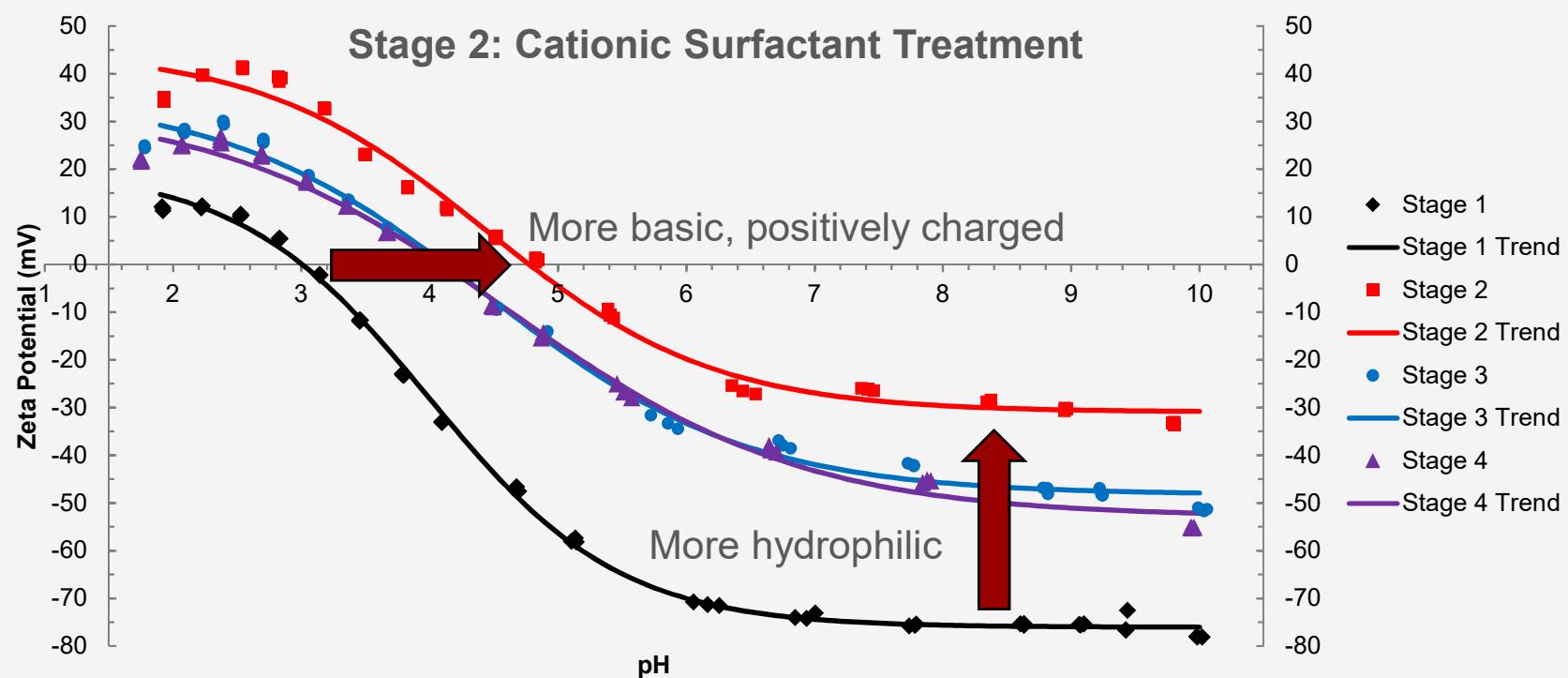


S. Temmel et al., Prog. Colloid Polym. Sci. 132 (2005) 54

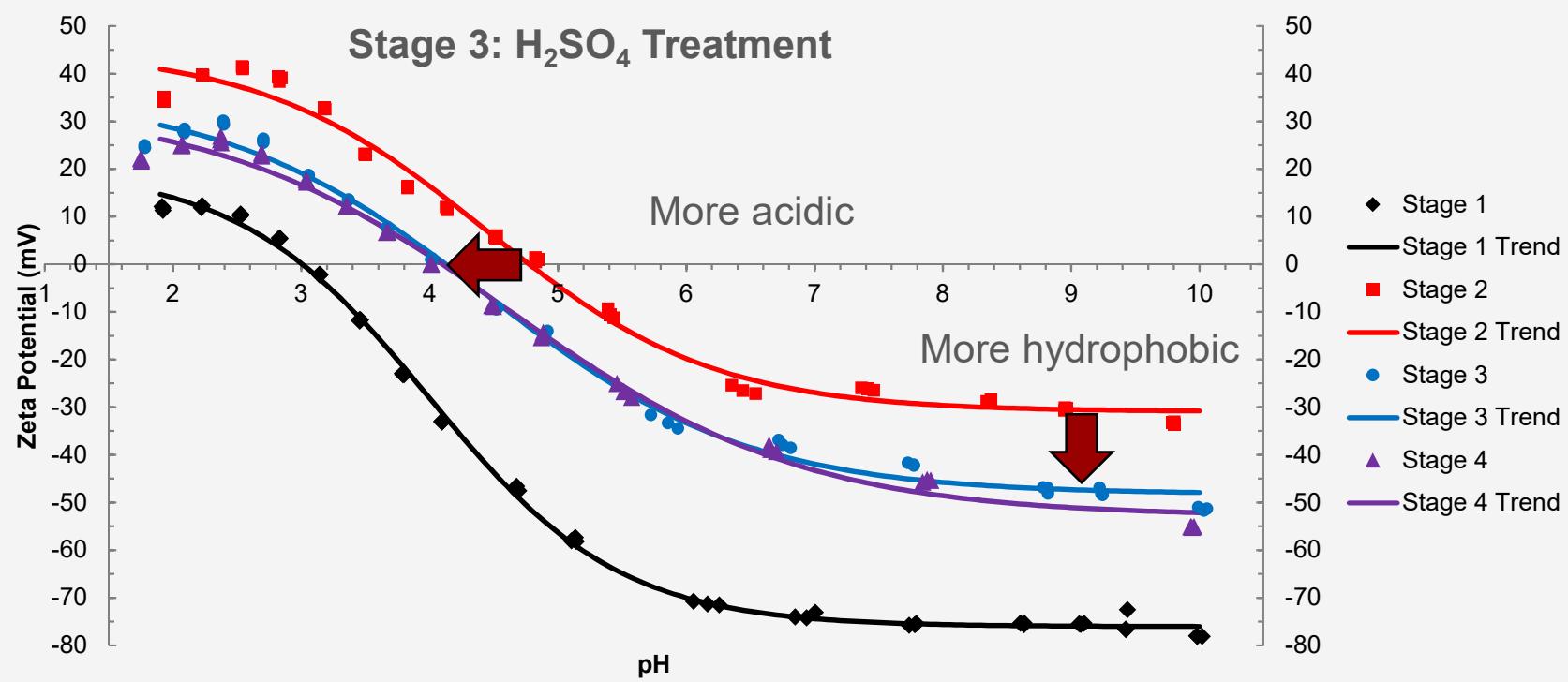
## Polymer surface activation



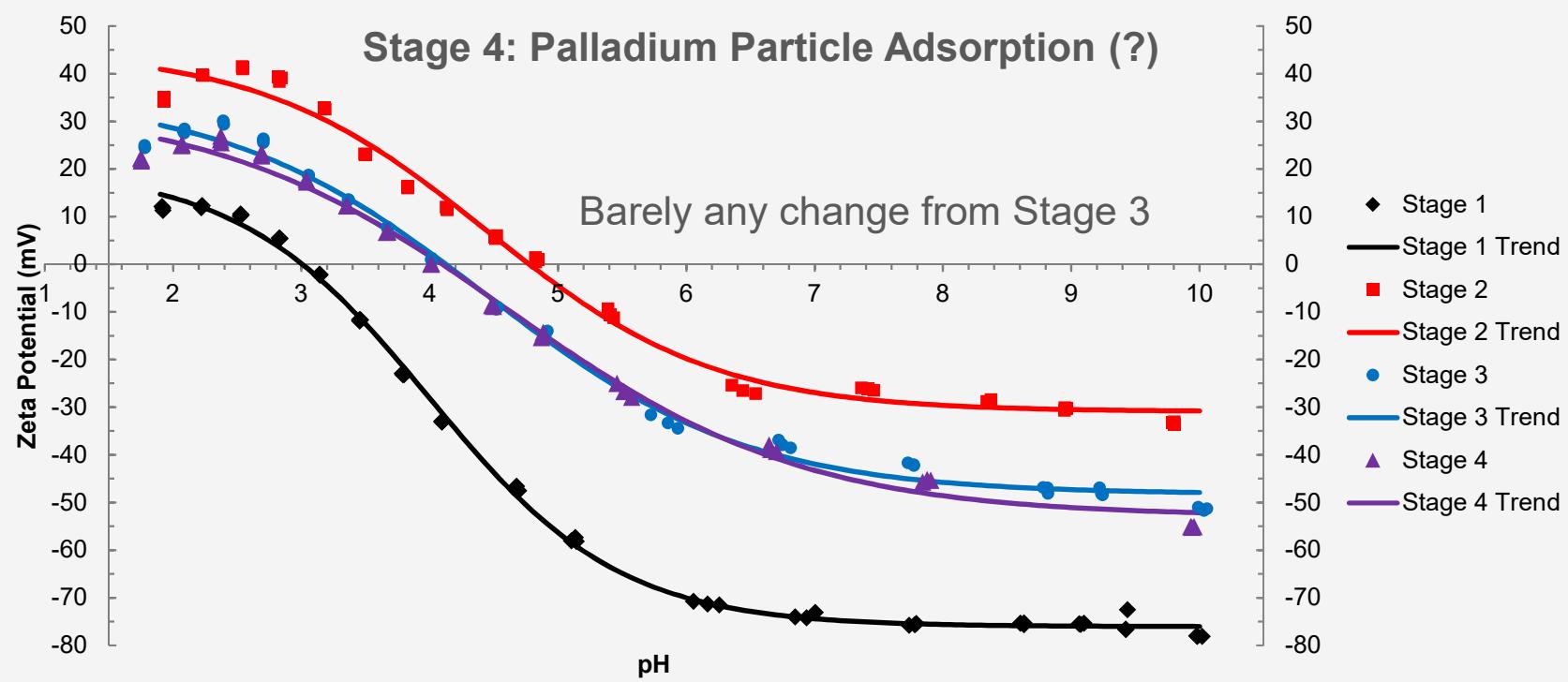
# Step-by-Step Process Treatment of Plastic for Semiconductor Applications



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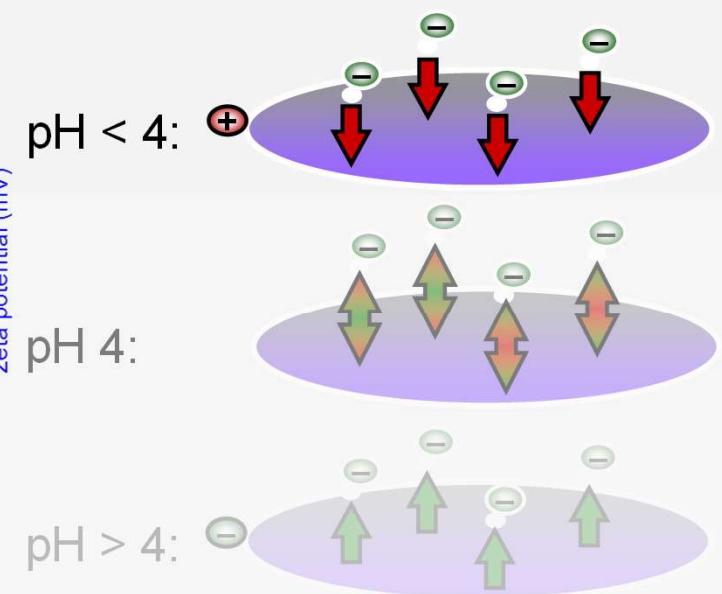
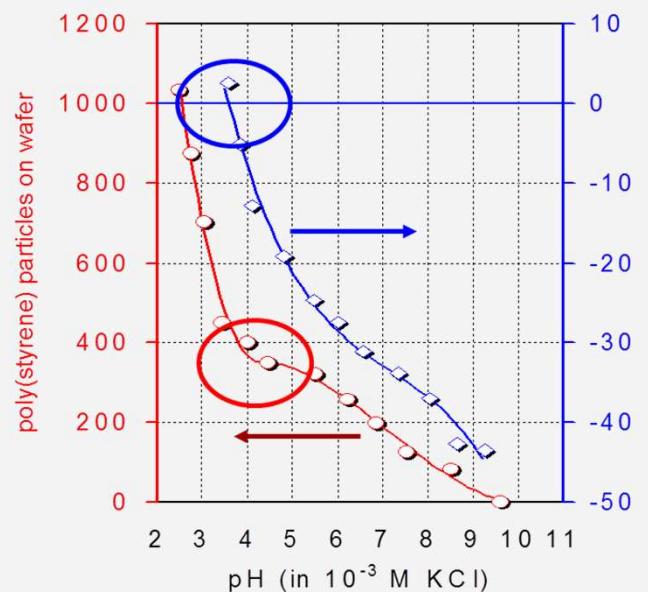
# Step-by-Step Process Treatment of Plastic for Semiconductor Applications



# Particle Adsorption on Silicon Wafer

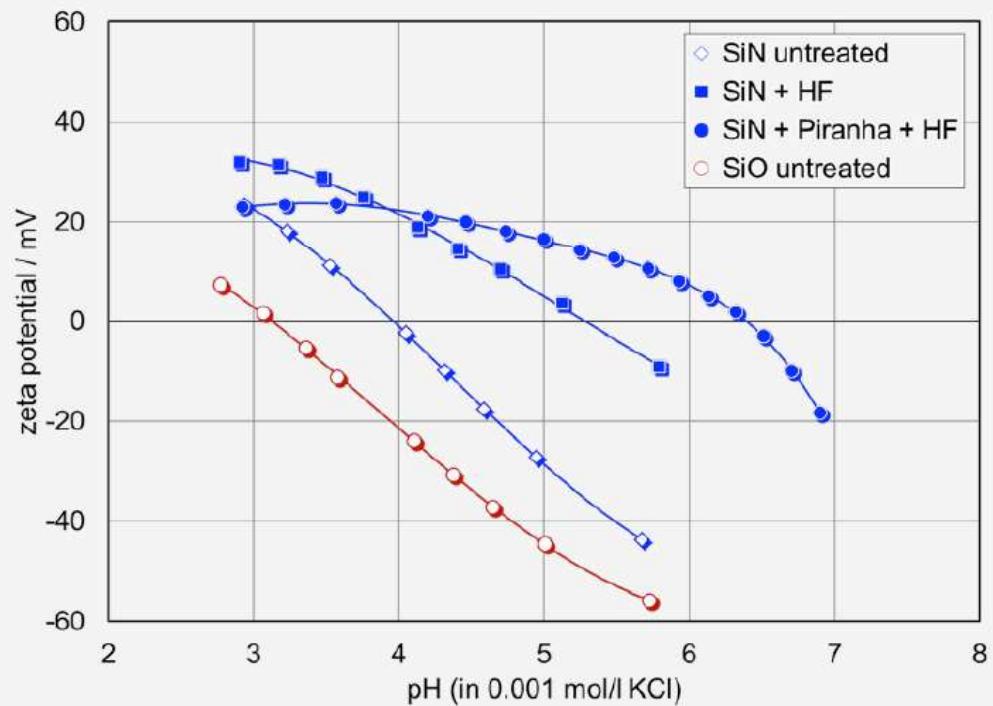


Adsorption of  
negatively charged  
poly(styrene)  
particles on wafer  
surface



Source: D.Jan, S.Raghavan, Proc. 3<sup>rd</sup> Int. Symp. on Cleaning Technology in Semiconductor Device Manufacturing (1993)

## Wafer cleaning efficiency



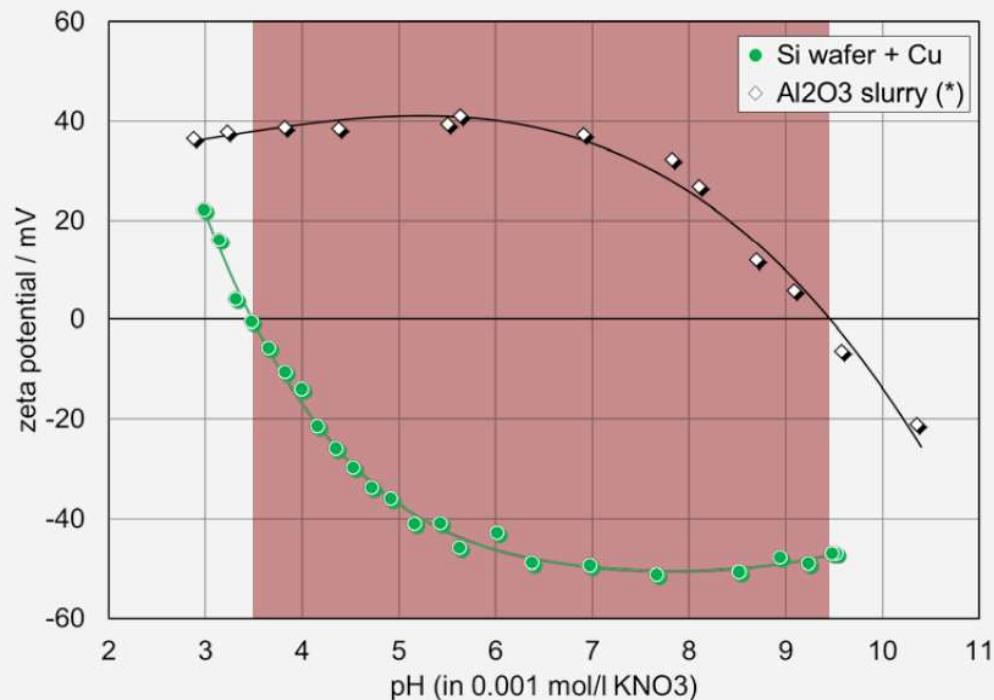
SiN .... silicon nitride wafer

SiO .... silicon oxide wafer

Piranha:  $\text{H}_2\text{SO}_4:\text{H}_2\text{O}_2 = 3:1$ ,  
oxidative removal of organic  
contaminant

HF: removal of silicon oxide

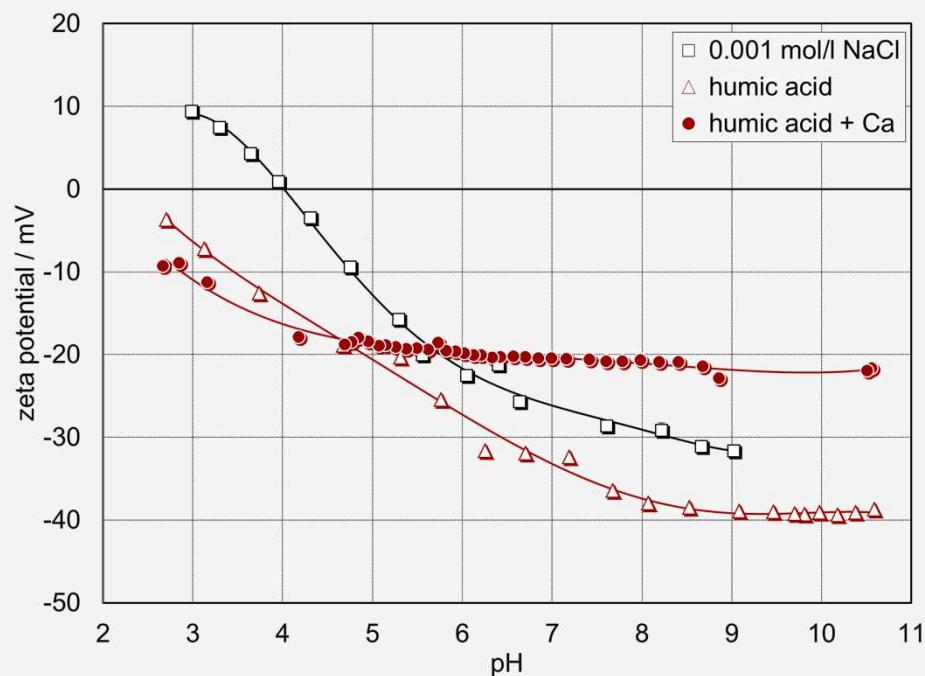
## Chemical Mechanical Polishing



- CMP process uses abrasive particles (e.g., Al<sub>2</sub>O<sub>3</sub> or SiO<sub>2</sub> slurries)
- After CMP, particles must not adhere to the wafer surface
- Electrostatic repulsion requires equally charged wafer and particle surfaces

(\* measured by ELS)

## Membrane fouling

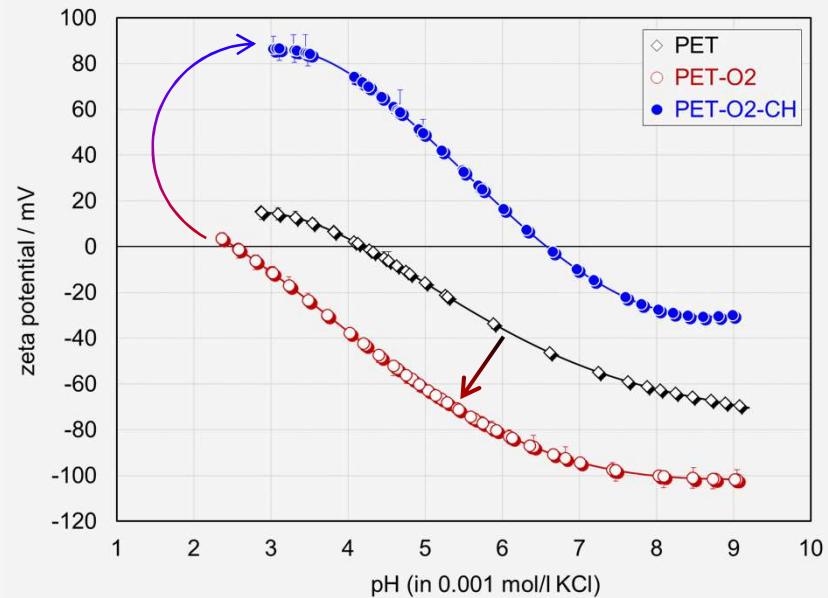


- Thin-film composite polyamide membrane for reverse osmosis
- Virgin membrane  $\zeta$  determined in 0.001 mol/l NaCl
- Adsorption of 100 mg/l humic acid
- Adsorption of 10 mg/l  $\text{Ca}^{2+}$

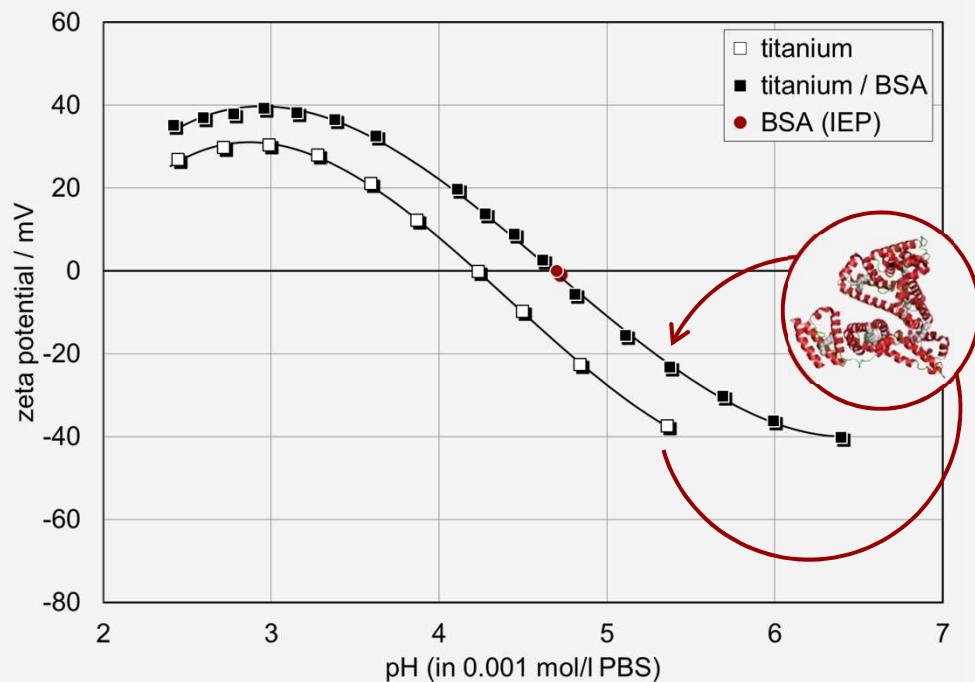
## SurPASS 3 for polymer applications

### Antimicrobial coatings

- PET  
poly(ethylene terephthalate) foil
- PET-O<sub>2</sub>  
PET foil treated with oxygen plasma
- PET-O<sub>2</sub>-CH  
PET foil treated with oxygen plasma and coated with chitosan

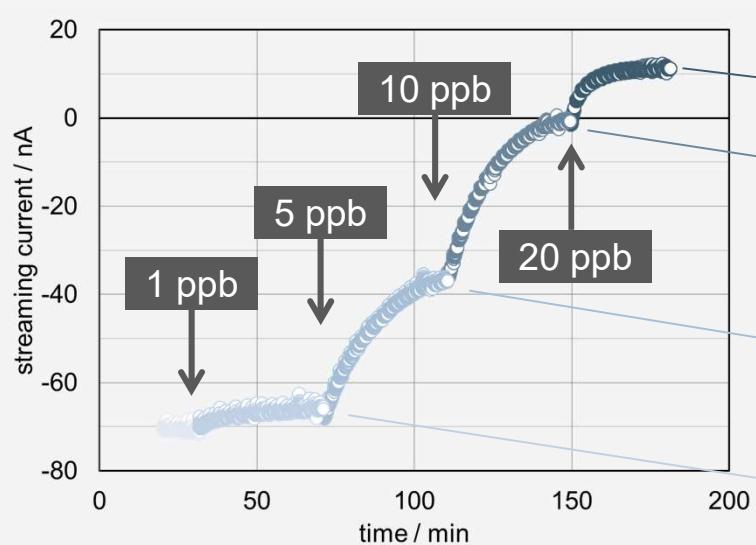


## Protein adsorption

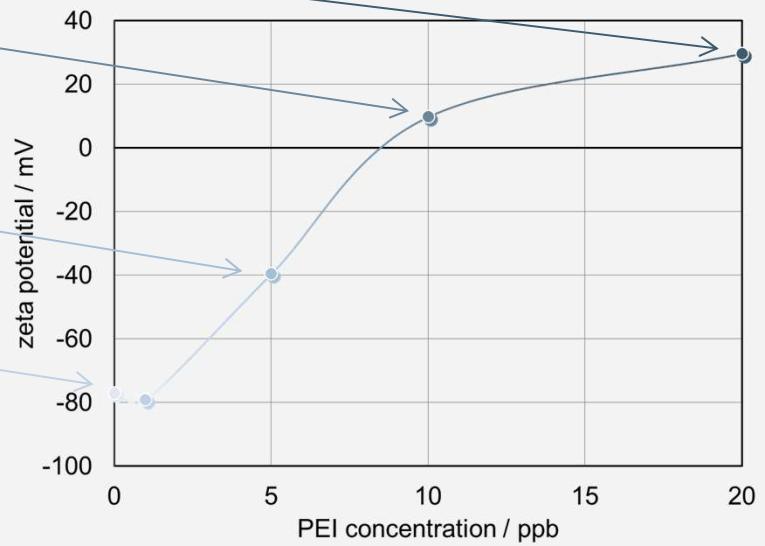


- Adsorption of BSA (bovine serum albumin) on titanium
- Isoelectric point (IEP) of titanium | BSA matches IEP of BSA in solution

# Monitoring of Adsorption Processes

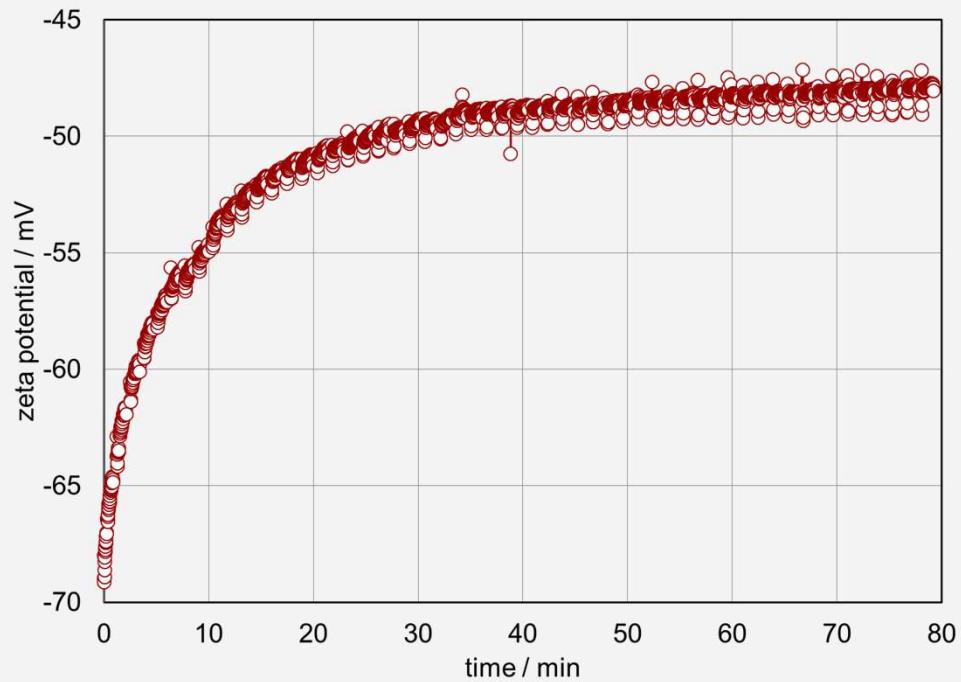


- Adsorption of poly(ethylene imine), PEI, on silicon oxide wafer



## SurPASS 3 for biomaterial applications

### Protein adsorption



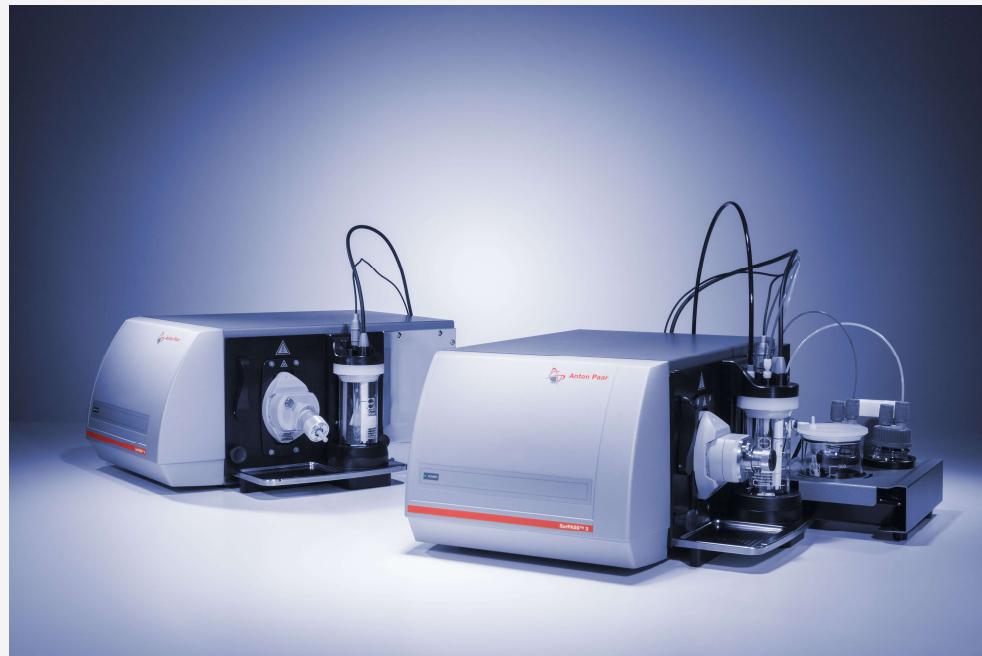
- Adsorption kinetics of bovine serum albumin (BSA) on glass
- 0.2 mg/ml BSA
- 0.001 mol/l PBS, pH 6.5



**Thank you !**

**Please send your Questions in the Chat Box**

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